

L Number	Hits	Search Text	DB	Time stamp
4	0	(((silylation and heat\$3) and pin) or (((118/715,724,725,726).CCLS.) and (heat or heated or heating) and (lift adj pin)) or (((118/715,724,725,726).CCLS.) and ((lift adj pin) with (sweep) adj gas))) or (((118/715,724,725,726).CCLS.) and (lift adj pin) with gas)) or (((118/715,724,725,726).CCLS.) and (gas adj ring)) or ((heat or heating or heated) and (lift adj pin) and (gas near ring)) or (((heat or heating or heated) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20021022) or (((preheat or preheated or preheating) or (pre adj (heat or heating or heated))) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20031104	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/11/04 16:34
5	85	(((silylation and heat\$3) and pin) or (((118/715,724,725,726).CCLS.) and (heat or heated or heating) and (lift adj pin)) or (((118/715,724,725,726).CCLS.) and ((lift adj pin) with (sweep) adj gas))) or (((118/715,724,725,726).CCLS.) and (lift adj pin) with gas)) or (((118/715,724,725,726).CCLS.) and (gas adj ring)) or ((heat or heating or heated) and (lift adj pin) and (gas near ring)) or (((heat or heating or heated) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20021022) or (((preheat or preheated or preheating) or (pre adj (heat or heating or heated))) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20030718	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/11/04 17:17
6	86	(((silylation and heat\$3) and pin) or (((118/715,724,725,726).CCLS.) and (heat or heated or heating) and (lift adj pin)) or (((118/715,724,725,726).CCLS.) and ((lift adj pin) with (sweep) adj gas))) or (((118/715,724,725,726).CCLS.) and (lift adj pin) with gas)) or (((118/715,724,725,726).CCLS.) and (gas adj ring)) or ((heat or heating or heated) and (lift adj pin) and (gas near ring)) or (((heat or heating or heated) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20021022) or (((preheat or preheated or preheating) or (pre adj (heat or heating or heated))) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20030717	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/11/04 17:19

7	1	((((silylation and heat\$3) and pin) or (((118/715,724,725,726).CCLS.) and (heat or heated or heating) and (lift adj pin)) or (((118/715,724,725,726).CCLS.) and ((lift adj pin) with ((sweep) adj gas))) or (((118/715,724,725,726).CCLS.) and ((lift adj pin) with gas)) or (((118/715,724,725,726).CCLS.) and (gas adj ring)) or ((heat or heating or heated) and (lift adj pin) and (gas near ring)) or (((heat or heating or heated) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20021022) or (((preheat or preheated or preheating) or (pre adj (heat or heating or heated))) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20030717) not ((((((silylation and heat\$3) and pin) or (((118/715,724,725,726).CCLS.) and (heat or heated or heating) and (lift adj pin)) or (((118/715,724,725,726).CCLS.) and ((lift adj pin) with ((sweep) adj gas))) or (((118/715,724,725,726).CCLS.) and ((lift adj pin) with gas)) or (((118/715,724,725,726).CCLS.) and (gas adj ring)) or ((heat or heating or heated) and (lift adj pin) and (gas near ring)) or (((heat or heating or heated) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20021022) or (((preheat or preheated or preheating) or (pre adj (heat or heating or heated))) and (lift adj pin) and (ring)) and (substrate or wafer))) and @pd>=20030718)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB; USOCR	2003/11/04 17:19
---	---	---	---	------------------